Amendment to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

(Original) An excimer or molecular fluorine laser system, comprising:

 a discharge chamber filled with a gas mixture at least including molecular fluorine

and a buffer gas;

a plurality of electrodes within the discharge chamber connected to a discharge circuit for energizing the gas mixture;

a resonator including a pair of resonator reflecting surfaces disposed on either side of the discharge chamber for generating a laser beam, said resonator further including a deformable third reflecting surface disposed between the pair of resonator reflecting surfaces;

a line-narrowing/selection unit within the resonator for narrowing the bandwidth of the laser beam;

a detector for detecting the bandwidth of the laser beam; and

a processor for receiving a signal indicative of said bandwidth from said detector and controlling a surface contour of said deformable third reflecting surface to control said bandwidth in a feedback arrangement.

- 2. (Original) The laser system of Claim 1, wherein said deformable third reflecting surface is a highly reflective mirror.
- 3. (Original) The laser system of Claim 1, wherein said deformable third reflecting surface is a cylindrical mirror.
- 4. (Original) The laser system of Claim 1, wherein said deformable third reflecting surface is a spherical mirror.

- 5. (Original) The laser system of Claim 1, wherein said line-narrowing/selection unit includes a beam expander and dispersive element, and wherein said deformable third reflecting surface is disposed between said beam expander and said dispersive element.
- 6. (Original) The laser system of Claim 1, wherein said line-narrowing/selection unit includes a dispersive element, and wherein said deformable third reflecting surface is disposed just before said dispersive element.
- 7. (Currently amended) A line-narrowed excimer or molecular fluorine laser system, comprising:

a discharge chamber filled with a gas mixture at least including molecular fluorine and a buffer gas;

a plurality of electrodes within the discharge chamber connected to a discharge circuit for energizing the gas mixture;

a resonator including a pair of resonator reflecting surfaces disposed on either side of the discharge chamber for generating a laser beam, said resonator further including a third reflecting surface which is deformable and disposed between the pair of resonator reflecting surfaces; and

a third reflecting surface disposed between the pair of resonator reflector surfaces, the third reflecting surface being deformable such that a surface contour of the third reflecting surface can be adjusted to control the bandwidth of the laser beam.

a line narrowing/selection unit within the resonator for narrowing the bandwidth of the laser beam.

- 8. (Original) The laser system of Claim 7, further comprising deformation means for controllably adjusting the surface contour of said deformable third reflecting surface.
- 9. (Currently amended) The laser system of Claim 7, wherein said <u>further</u> comprising a line-narrowing/selection unit <u>includes including</u> a beam expander and dispersive element, and wherein said deformable third reflecting surface is disposed between said beam expander and said dispersive element.

- 10. (Currently amended) The laser system of Claim 7, wherein said further comprising a line-narrowing/selection unit includes including a dispersive element, and wherein said deformable third reflecting surface is disposed just before said dispersive element.
- 11. (Original) The laser system of Claim 7, further comprising a processor for automatically adjusting the bandwidth of said laser by sending a signal to adjust said surface contour.
- 12. (Original) The laser system of Claim 11, further comprising a detector for detecting the bandwidth of the laser system and communicating bandwidth information to the processor which controls said bandwidth in a feedback arrangement.
- 13. (Currently amended) A line-narrowed excimer or molecular fluorine laser system, comprising:
 - a discharge chamber filled with a gas mixture at least including molecular fluorine and a buffer gas;
 - a plurality of electrodes within the discharge chamber connected to a discharge circuit for energizing the gas mixture;
 - a resonator including a pair of resonator reflecting surfaces disposed on either side of the discharge chamber for generating a laser beam, said resonator further including a third reflecting surface disposed between the pair of resonator reflecting surfaces and having a surface contour which is deformable in order to control the bandwidth of the laser beam and disposed between the pair of resonator reflecting surfaces;
 - a line-narrowing/selection unit within the resonator for narrowing the bandwidth of the laser beam; and
 - a spectrometer for measuring the bandwidth of said laser beam.
- 14. (Currently amended) The laser system of Claim 13, further comprising a processor for receiving data from the spectrometer corresponding to a current bandwidth and for

outputting a signal to adjust [[a]] the surface contour of the deformable third reflecting surface corresponding to a desired bandwidth.

- 15. (Original) The laser system of Claim 13, wherein said line-narrowing/selection unit includes a beam expander and dispersive element, and wherein said deformable third reflecting surface is disposed between said beam expander and said dispersive element.
- 16. (Original) The laser system of Claim 13, wherein said line-narrowing/selection unit includes a dispersive element, and wherein said deformable third reflecting surface is disposed just before said dispersive element.
- 17. (Currently amended) A line-narrowed excimer or molecular fluorine laser system, comprising:
 - a discharge chamber filled with a gas mixture at least including molecular fluorine and a buffer gas;
 - a plurality of electrodes within the discharge chamber connected to a discharge circuit for energizing the gas mixture;
 - a resonator including a pair of resonator reflecting surfaces disposed on either side of the discharge chamber for generating a laser beam, said resonator further including a third reflecting surface which is deformable and disposed between the pair of resonator reflecting surfaces and having a surface contour which is deformable;
 - a line-narrowing/selection unit within the resonator for narrowing the bandwidth of the laser beam; and
 - a detector for detecting [[a]] at least one parameter of the laser system including the bandwidth of the laser beam; and
 - a processor for receiving a signal indicative of said <u>at least one</u> laser system parameter from said detector and controlling a surface contour of said deformable third reflecting surface in a feedback arrangement <u>in order to control at least the bandwidth of the laser beam</u>.

- 18. (Original) The laser system of Claim 17, wherein said deformable third reflecting surface is a cylindrical mirror.
- 19. (Original) The laser system of Claim 17, wherein said deformable third reflecting surface includes a curvature in two orthogonal cross-sectional beam axis directions.
- 20. (Currently amended) The laser system of Claim 17, wherein said laser system parameter is laser beam bandwidth linewidth.
- 21. (Original) The laser system of Claim 17, wherein said line-narrowing/selection unit includes a beam expander and dispersive element, and wherein said deformable third reflecting surface is disposed between said beam expander and said dispersive element.
- 22. (Original) The laser system of Claim 17, wherein said line-narrowing/selection unit includes a dispersive element, and wherein said deformable third reflecting surface is disposed just before said dispersive element.
- 23. (Currently amended) A line-narrowed excimer or molecular fluorine laser system, comprising:
 - a discharge chamber filled with a gas mixture at least including molecular fluorine and a buffer gas;
 - a plurality of electrodes within the discharge chamber connected to a discharge circuit for energizing the gas mixture;
 - a resonator including a pair of resonator reflecting surfaces disposed on either side of the discharge chamber for generating a laser beam, said resonator further including a third reflecting surface which is deformable and disposed between the pair of resonator reflecting surfaces and having a surface contour that can be modified to control the bandwidth of the laser beam;
 - a line-narrowing/selection unit within the resonator for narrowing the bandwidth of the laser beam, and

wherein said line-narrowing/selection unit includes a dispersive element, and wherein said deformable third reflecting surface is disposed just before said dispersive element.

- 24. (Original) The laser system of Claim 23, wherein said line-narrowing/selection unit further includes a beam expander, and wherein said deformable third reflecting surface is disposed between said beam expander and said dispersive element.
- 25. (Currently amended) A method of adjusting the bandwidth of a line-narrowed excimer or molecular fluorine laser including a discharge chamber having a gas mixture and a plurality of electrodes therein within a resonator for generating a laser beam, the resonator including a pair of resonator reflectors disposed on either side of the discharge chamber for generating a laser beam and a deformable third reflecting surface disposed between the pair of resonator reflectors, comprising the operations:

applying electrical pulses to the plurality of electrodes within said discharge chamber for energizing the gas mixture therein;

measuring a bandwidth of the laser beam; and

adjusting a surface contour of said deformable third reflecting surface for adjusting the bandwidth of the laser beam based on the measured bandwidth.

- 26. (Original) The method of Claim 25, further comprising the operations transmitting a signal to a processor corresponding to the measured bandwidth, and transmitting another signal to the deformable third reflecting surface corresponding to a selected surface contour adjustment.
 - 27. (Currently amended) An excimer or molecular fluorine laser, comprising: a dishearge discharge chamber filled with a gas mixture;
 - a plurality of electrodes in the discharge chamber connected to a pulse power circuit for energizing the gas mixture; and
 - a resonator for generating a laser beam, including one or more linenarrowing/selection optics, a pair of resonator reflectors and a deformable third reflecting

surface <u>disposed between the pair of resonator reflectors</u> having an adjustable surface contour for matching the wavefront of the beam to reduce the bandwidth narrowed/selected by the line-narrowing/selection unit.

- 28. (Original) The laser of Claim 27, wherein the one or more linenarrowing/selection optics include a dispersive element, and wherein the deformable third reflecting surface is disposed just before the dispersive element.
- 29. (Original) The laser of Claim 28, wherein the one or more linenarrowing/selection optics include a beam expander, and wherein the deformable third reflecting surface is disposed between the beam expander and the dispersive element.
- 30. (Original) The laser of Claim 29, wherein the dispersive element is a grating serving as one of said pair of resonator reflectors.
- 31. (Original) The laser of claim 28, the resonator further comprising an interferometric device.
- 32. (Original) The laser of claim 27, wherein the adjustable surface contour of the deformable third reflecting surface is automatically feedback controlled using a processor and a detector for monitoring a spectral parameter of the laser beam.
- 33. (Currently amended) A resonator for an excimer or molecular fluorine laser system, comprising:
 - a discharge chamber for filling with a gas mixture;
 - a plurality of electrodes within the discharge chamber for connecting to a discharge circuit for energizing the gas mixture;
 - a pair of resonator reflectors for generating a laser beam; and
 - a bi-directional bandwidth controlled folding mirror assembly <u>disposed between</u> the pair of resonator reflectors, the mirror assembly including:

a folding mirror;

a coupling plate coupling with the mirror;

an adjustment spindle penetrating through a cavity defined in the coupling plate, and

wherein screwing the adjustment spindle in a first direction increases a concavity of a surface contour of the folding mirror, and screwing the adjustment spindle in a second direction opposite to said first direction decreases the concavity of the surface contour of the folding mirror.

- 34. (Original) The resonator of Claim 33, further comprising at least one spring disposed between a portion of said coupling plate and a head of said adjustment spindle.
- 35. (Original) The resonator of Claim 33, further comprising a movable nut on the adjustment spindle.
- 36. (Original) The resonator of Claim 33, further comprising a motor for motorizing the adjustment spindle.
- 37. (Original) The resonator of Claim 33, wherein the surface contour of the folding mirror is convex.
- 38. (Original) The resonator of Claim 33, wherein the surface contour of the folding mirror is concave.
- 39. (Original) The resonator of Claim 33, further comprising a line narrowing/selection unit including at least one optical element having an adjustable orientation for tuning a wavelength of the laser beam, and wherein said adjusting of said surface contour of said folding mirror adjusts the bandwidth of the laser beam.
- 40. (Original) The resonator of Claim 39, wherein the line narrowing/selection unit includes a beam expander and a dispersive element, and wherein the folding mirror is disposed between the beam expander and the dispersive element.

- 41. (Original) The resonator of Claim 33, wherein the bi-directional bandwidth controlled folding mirror assembly is configured such that the surface contour of the folding mirror is adjustable based on signals received from a detector for monitoring the bandwidth of the laser beam.
- 42. (Currently amended) A resonator for an excimer or molecular fluorine laser system, comprising:
 - a discharge chamber for filling with a gas mixture;
 - a plurality of electrodes within the discharge chamber for connecting to a discharge circuit for energizing the gas mixture;
 - a pair of resonator reflectors for generating a laser beam; and
 - a bi-directional bandwidth controlled folding mirror assembly <u>disposed between</u> the pair of resonator reflectors, the mirror assembly including:
 - a folding mirror;
 - a coupling plate coupling with the mirror;
 - a piezo transducer coupled with the coupling plate, and
 - wherein operating the piezo transducer in a first direction increases a concavity of the folding mirror, and operating the piezo transducer in a second direction opposite to said first direction decreases a concavity of the folding mirror.
 - 43. (Original) The assembly of Claim 42, wherein the folding mirror is convex.
 - 44. (Original) The assembly of Claim 42, wherein the folding mirror is concave.
- 45. (Original) The resonator of Claim 42, further comprising a line narrowing/selection unit including at least one optical element having an adjustable orientation for tuning a wavelength of the laser beam, and wherein said adjusting of said surface contour of said folding mirror adjusts the bandwidth of the laser beam.

- 46. (Original) The resonator of Claim 42, wherein the line narrowing/selection unit includes a beam expander and a dispersive element, and wherein the folding mirror is disposed between the beam expander and the dispersive element.
- 47. (Original) The resonator of Claim 42, wherein the bi-directional bandwidth controlled folding mirror assembly is configured such that the surface contour of the folding mirror is adjustable based on signals received from a detector for monitoring the bandwidth of the laser beam.